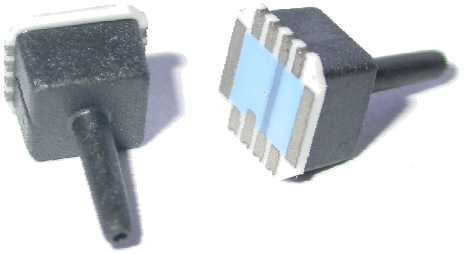
HYBRID SERIES PRESSURE SENSORS

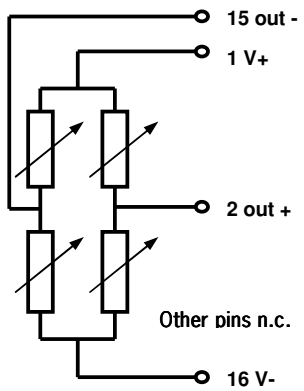
The hybrid series MEMS made piezoresistive pressure sensors provides a convenient way to use Surface mount technology with a flexible way of air connection. Due to the production process these sensors are ideal for high volume applications and automated assy.
Two kind of air connections are available, a cap with hole and a cap using 1/8" tube connection.
Available in: absolute version and gauge version; Pressure range 15 psi Absolute.



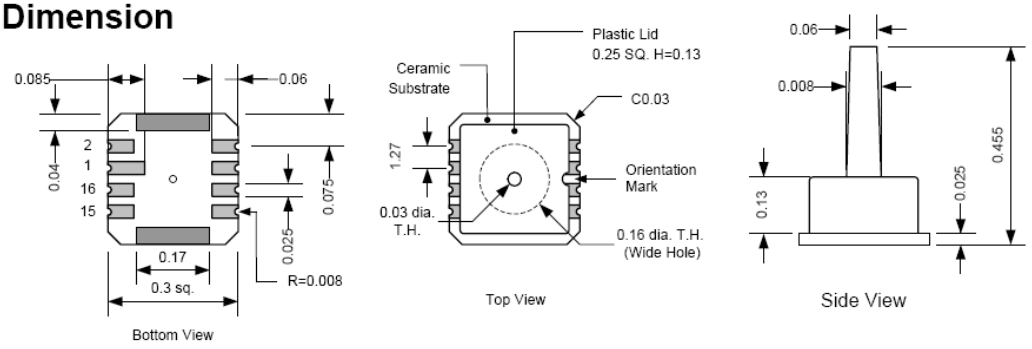
Electrical Characteristics

Performance Characteristic at Vcc =5V excitation @ 25 °C.

Parameter	Min	Typ	Max	Units.
Supply Voltage		5	10	V
Pressure range (fs)	0		15	psi
Offset	-30	0	30	mV
Span Output	70	100	130	mV
Bridge Impedance	4	5	6	KΩ
Linearity		±0.3		%FS
TC Span (0-50 °C)	-14	-19	-24	%FS/100°C
TC Offset (0-50 °C)		±7		%FS/100°C
Response time		1		ms
Pressure overload			3X	psi
Operating temperature	-40		85	℃
Storage temperature	-40		125	℃



Dimension



Note: All sizes in Inches
Max soldering 260 °C / 7 seconds